

1 ABSTRACT OF THE DISCLOSURE

2 A semiconductor processing workpiece support which includes a
3 detection subsystem that detects whether a wafer or other workpiece is
4 present. The preferred arrangement uses an optical beam emitter and
5 an optical beam detector mounted along the back side of a rotor which
6 acts as a workpiece holder. The emitted beam passes through the
7 workpiece holder and is reflected by any workpiece present in the
8 workpiece holder. The preferred units include both an optical emitter
9 and pair of detectors. The detection is preferably able to discriminate
10 on the basis of the angle of the reflected beam, so that a portion of
11 the beam reflected by the workpiece holder is not considered or
12 minimized.

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